which they are connected at least indirectly to one another, and at least one of the synchro rings and/or the intermediate ring consisting of a metallic basic material, wherein at least one of the synchro rings and the intermediate ring consist of the metallic basic material which is nitride-hardened in such a way that, by process parameters being set during nitride-hardening, one of a non-metallic γ' -connecting layer and a non-metallic ε -connecting layer is formed on a conical surface of at least one of the synchro rings and the intermediate ring.

- 13. (NEW) Synchronizing device according to Claim 12, wherein a γ' -connecting layer is formed which consists of Fe₄N.
- 14. (NEW) Synchronizing device according to Claim 12, wherein a ϵ -connecting layer is formed which consists of Fe_{2.3}N.
- 15. (NEW) Synchronizing device according to Claim 12, wherein at least one of the synchro rings and the intermediate ring is plasma-nitride-hardened.
- 16. (NEW) Synchronizing device according to Claim 12, wherein the metallic basic material of at least one of the synchro rings and the intermediate ring is a sintered material.

- 17. (NEW) Synchronizing device according to Claim 12, wherein the metallic basic material of at least one of the synchro rings and the intermediate ring is a sinter-forged material.
- 18. (NEW) Synchronizing device according to Claim 12, wherein the metallic basic material of at least one of the synchro rings and the intermediate ring is a hardenable steel.
- 19. (NEW) Synchronizing device according to Claim 12, wherein the nitriding depth is 200 to 800 μm .
- 20. (NEW) Synchronizing device according to Claim 12, wherein the γ' -connecting layer and the ϵ -connecting layer is 1 to 20 μm , preferably approximately 10 μm , thick.
- 21. (NEW) Synchronizing device according to Claim 12, wherein the intermediate ring is arranged between the inner synchro ring and the outer synchro ring, the conical surfaces of the intermediate ring having a friction layer, and the γ' or ϵ connecting layer being in each case located on the conical surfaces of the two synchro rings in the outer region.

- 22. (NEW) Synchronizing device according to Claim 12, wherein the inner synchro ring or the outer synchro ring is firmly connected to a gearwheel, the γ' or ϵ -connecting layer being applied to one synchro ring, and the friction layer being applied to the other synchro ring.
- 23. (NEW) Synchronizing device according to Claim 13, wherein a ϵ -connecting layer is formed which consists of Fe_{2.3}N.
- 24. (NEW) Synchronizing device according to Claim 13, wherein at least one of the synchro rings and the intermediate ring is plasma-nitride-hardened.
- 25. (NEW) Synchronizing device according to Claim 14, wherein at least one of the synchro rings and the intermediate ring is plasma-nitride-hardened.
- 26. (NEW) Synchronizing device according to Claim 13, wherein the metallic basic material of at least one of the synchro rings and the intermediate ring is a sintered material.
- 27. (NEW) Synchronizing device according to Claim 14, wherein the metallic basic material of at least one of the synchro rings and the intermediate ring is a sintered material.

28. (NEW) Synchronizing device according to Claim 13, wherein the metallic basic material of at least one of the synchro rings and the intermediate ring is a sinter-forged material.

- 29. (NEW) Synchronizing device according to Claim 14, wherein the metallic basic material of at least one of the synchro rings and the intermediate ring is a sinter-forged material.
- 30. (NEW) Synchronizing device according to Claim 13, wherein the metallic basic material of at least one of the synchro rings and the intermediate ring is a hardenable steel.
- 31. (NEW) Synchronizing device according to Claim 14, wherein the metallic basic material of at least one of the synchro rings and the intermediate ring is a hardenable steel.

32. (NEW) Synchronizing device according to Claim 13, wherein the nitriding depth is 200 to 800 μm .

33. (NEW) Synchronizing device according to Claim 14, wherein the nitriding depth is 200 to 800 μm .

34. (NEW) A synchronizing device assembly for a vehicle shift transmission, comprising:

a first synchro ring with a first friction surface, and a second synchro ring with a second friction surface which in use selectively engages the first friction surface,

wherein said first synchro ring is formed of a metallic base material, and

wherein said first synchro ring is nitride hardened to form one of a non-metallic γ' -connecting layer and a non-metallic ϵ -connecting layer on said first friction surface.

35. (NEW) A synchronizing device assembly according to Claim 34, wherein said first synchro ring is nitride hardened to form a non-metallic γ' -connecting layers of Fe₄N on said first friction surface.

36. (NEW) A synchronizing device assembly according to Claim 34, wherein said first synchro ring is nitride hardened to form a non-metallic ϵ -connecting layers of Fe_{2.3}N on said first friction surface.

37. (NEW) A synchronizing device assembly according to Claim 34, wherein said first synchro ring is plasma-nitride-hardened.

38. (NEW) A synchronizing device assembly according to Claim 34, wherein said first synchro ring is formed of a sintered material.

- 39. (NEW) A synchronizing device assembly according to Claim 34, wherein said first synchro ring is formed of a sinterforged material.
- 40. (NEW) A synchronizing device assembly according to Claim 34, wherein said first synchro ring is formed of a hardenable steel.
- 41. (NEW) A synchronizing device assembly according to Claim 34, wherein the nitriding depth on the first synchronizing is between 200 and 800 μg .
- 42. (NEW) A synchronizing device assembly according to Claim 34, wherein the connecting layer is between 1 to 20 $\mu \rm m$ thick.
- 43. (NEW) A synchronizing device assembly according to Claim 34, wherein the connecting layer is 10 μm thick.

44. (NEW) A method of making synchronizing device assembly for a vehicle shift transmission, comprising:

a first synchro ring with a first friction surface, and a second synchro ring with a second friction surface which in use selectively engages the first friction surface,

said method comprising forming said first synchro ring of a metallic base material, and

nitride hardening said first synchro ring to form one of a non-metallic $\gamma^\prime\text{-connecting layer}$ and a non-metallic $\epsilon\text{-connecting layer}$ on said first friction surface.

45. (NEW) A method according to Claim 44, wherein said first synchro ring is nitride hardened to form a non-metallic γ' -connecting layers of Fe₄N on said first friction surface.

- 46. (NEW) A synchronizing device assembly according to Claim 44, wherein said first synchro ring is nitride hardened to form a non-metallic ϵ -connecting layers of Fe_{2.3}N on said first friction surface.
- 47. (NEW) A synchronizing device assembly according to Claim 44, wherein said first synchro ring is plasma-nitride-hardened.